



PATENT

Case Docket No. IMEC306.001AUS

Date: April 29, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Szlufcik, et al.
Appl. No. : 10/609015
Filed : 27-Jun-2003
For : SEMICONDUCTOR ETCHING
PASTE AND THE USE
THEREOF FOR LOCALIZED
ETCHING OF
SEMICONDUCTOR
SUBSTRATES
Examiner : Unassigned
Group Art Unit : 1765

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

April 29, 2004

(Date)

Rose M. Thiessen, Reg. No. 40,202


TRANSMITTAL LETTER

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement.
- (X) A PTO Form 1449 with seventeen (17) references.
- (X) The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.
- (X) Return prepaid postcard.


Rose M. Thiessen
Registration No. 40,202
Attorney of Record
Customer No. 20,995
(619) 235-8550



INFORMATION DISCLOSURE STATEMENT

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing seventeen (17) references that are also enclosed.

This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 4/29/04

By: 

Rose M. Thiessen
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(619) 235-8550

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
IMEC306.001AUSAPPLICATION NO.
10/609,015INFORMATION DISCLOSURE STATEMENT
BY APPLICANT

(USE SEVERAL SHEETS IF NECESSARY)

APPLICANT
Szlufcik, et al.FILING DATE
June 27, 2003GROUP
1765

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	1	4,605,689	08/12/86	Witheford, et al.			
	2	4,781,792	11/1/88	Hogan			
	3	5,296,043	03/22/94	Kawakami, et al.			
	4	5,461,002	10/24/95	Safir			
	5	5,688,366	11/18/97	Ichinose, et al.			
	6	5,698,451	12/16/97	Hanoka			
	7	5,726,065	03/10/98	Szlufcik, et al.			
	8	5,894,853	04/20/99	Fujisaki, et al.			
	9	5,949,123	09/07/99	Lee, et al.			
	10	6,384,317	05/07/02	Kerschaver, et al.			
	11	6,388,187	05/14/02	Takeyama, et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	12	EP0851511A1	07/01/98	Europe				
	13	EP0773590A1	05/14/97	Europe				X
	14	DE3422454A1	12/19/85	Germany				X

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	15	"High throughput laser isolation of crystalline silicon solar cells", G. Emanuel, 17 th European Photovoltaic Solar Energy Conference and Exhibition, Munich, Germany, Oct. 22-27, 2001.
	16	"A new passivation method for edge shunts of silicon solar cells", M. Al-Rifai, et al., 17 th European Photovoltaic Solar Energy Conference and Exhibition, Munich, Germany, Oct. 22-27, 2001.
	17	European Search Report of EP 03447176.3 dated September 3, 2003.

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100203

EXAMINER	DATE CONSIDERED
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	